



- (3506) 250/281 250/288
 - (3) ("4570068" | "4667100" | "5157260").PN.
 - (474) (250/281 250/288) and heater
 - (4910) remov\$ and electrospray
 - (328) removable and electrospray
 - (2) removable near3 electrospray
 - (3) ("5306412" | "5788166" | "6127680").PN.
 - (376) apci and electrospray
 - (460) 250/455.11
 - (113) 250/455.11 and electron
 - (6) ("4075496" | "4201920" | "4252413" | "4281251" | "4492873" | "5004926").PN.
 - (1) wo99/00801
 - (0) "9900801"
 - (5) anderberg and irradiation
 - (8) anderberg and irradiation
 - (9) "9900801"
 - (31) 250/455.11 and electron and (computer microprocessor)
 - (325) (arc near3 chamber) and alumina
 - (19) (arc near3 chamber) and (alumina near3 insulat\$4)
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USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM ☒ Plurals

Default operator:

☒ Highlight all hit terms initially

11 and alumina

	U		Document ID	Issue Date	Pages	Title	Current OR	Current XRef	Retrieval Clas	
1	<input type="checkbox"/>	<input type="checkbox"/>	US 20030136918 A1	20030724	11	SOFT IONIZATION DEVICE AND APPLICATIONS THEREOF	250/423R			Hartle
2	<input type="checkbox"/>	<input type="checkbox"/>	US 20030127433 A1	20030710	11	Automated electrode replacement apparatus for a plasma processing	219/121.56	250/423R; 313/359.1;		Sirkis.
3	<input type="checkbox"/>	<input type="checkbox"/>	US 20030122089 A1	20030703	15	Ion sources for ion implantation apparatus	250/492.21	250/423R; 250/425		Murre
4	<input type="checkbox"/>	<input type="checkbox"/>	US 20030042436 A1	20030306	49	Discharge electrode and discharge electrode manufacturing method	250/493.1			Horj, T
5	<input type="checkbox"/>	<input type="checkbox"/>	US 20030042435 A1	20030306	9	Powdered far-infrared radiator and method of making the same	250/493.1			Imai, I
6	<input type="checkbox"/>	<input type="checkbox"/>	US 20030038245 A1	20030227	13	Field ionizing elements and applications thereof	250/423R	250/287; 250/288;		Hartle
7	<input type="checkbox"/>	<input type="checkbox"/>	US 20020056816 A1	20020516	18	Surface plasmon enhanced illumination system	250/493.1			Stark, Hazar
8	<input type="checkbox"/>	<input type="checkbox"/>	US 6617810 B2	20030909	11	Multi-stage cavity cyclotron resonance accelerators	315/500	250/292; 250/423R;		Symon
9	<input type="checkbox"/>	<input type="checkbox"/>	US 6617806 B2	20030909	21	High brightness microwave lamp	315/248	313/113; 315/39		Kirkpa
10	<input type="checkbox"/>	<input type="checkbox"/>	US 6610986 B2	20030826	10	Soft ionization device and applications thereof	250/423R	250/286; 250/287;		Hartle
11	<input type="checkbox"/>	<input type="checkbox"/>	US 6597004 B2	20030722	9	Powdered far-infrared radiator and method of making the same	250/493.1	250/495.1; 252/500;		Imai, I
12	<input type="checkbox"/>	<input type="checkbox"/>	US 6566257 B2	20030520	12	Method for producing semiconductor device	438/682	257/E21.199; 257/E21.334;		Sueyo
13	<input type="checkbox"/>	<input type="checkbox"/>	US 6562418 B2	20030513	4	Microwave processing of pressed boron powders for use as cathodes	427/580	419/37; 419/38;		Morro
14	<input type="checkbox"/>	<input type="checkbox"/>	US 6559443 B2	20030506	14	Ionization apparatus and ionization method for mass spectrometry	250/288	250/281; 250/282;		Shiok
15	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6547458 B1	20030415	25	Optimized optical system design for endpoint detection	396/611	156/118; 156/250;		Janos
16	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6541917 B1	20030401	11	Section of pipe for a gas treatment device and device incorporating su	315/111.21	118/723MW		Rosta et al.
17	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6538251 B1	20030325	15	Radiation source assembly and transducer for analyzing gases or o	250/343	250/339.06; 250/341.7;		Weck
18	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6531704 B2	20030311	27	Nanotechnology for engineering the performance of substances	250/493.1	205/766		Yadav
19	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6525480 B1	20030225	18	Low power, linear geometry hall plasma source with an open electro	315/111.21	250/423R; 313/231.31;		Hargu
20	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6507142 B1	20030114	13	Plume shield for ion accelerators	313/239	250/423R;		Tilley